

MPS

Machine Protection System

The Machine Protection System (MPS) is an interlock system to turn off or reduce the rate of the beam in response to fault conditions that may either damage or cause unwanted activation of machine parts. The three active devices in the LCLS MPS are an abort kicker that is able to kick a single electron bunch, and a Pockels cell and mechanical shutter that block the laser light.

This page contains documentation and links to documentation on the MPS.

Documentation

LCLS MPS

PRD and ESD

See [LCLS MPS Sharepoint Site](#) for PRD and ESD Documents and Information.
See the [LCLS Requirement, Specification and Interface Documents](#) page for ESD documents.

[How to Add a New Link Node](#)

Interim MPS

PRD and ESD

See [LCLS MPS Sharepoint Site](#) for PRD documents and information.
See the [LCLS Requirement, Specification and Interface Documents](#) page for ESD documents.

ICD

[Interim MPS ICD](#) Last update 2006-05-03. Rev 0.

Mitigation Devices

[MPS Mechanical Shutter](#)

MPS Drawing Numbers

[MPS Drawing Numbers](#)